



## 极薄氧化物/6H-SiC结构的电学和光学性质研究

Pincik E<sup>1</sup>, Kobayashi H<sup>2</sup>, Madani M<sup>2</sup>, Rusnak J<sup>1</sup>, Takahashi M<sup>2</sup>, Mikula M<sup>3</sup>, Brunner R<sup>1</sup>

1. 斯洛伐克科学院物理研究所, Dubravská cesta 9, 845 11 Bratislava, Slovakia; 2. 科学与工业研究所, 大阪大学, Mihogaoka, Ibaraki, Osaka 567-0047, Japan; 3. 化学、食品技术和应用光化学系, Radlinskeho 9, SUT, 812 39 Bratislava, Slovakia

## On electrical and optical properties of very thin oxide/6H-SiC structures

Pincik E<sup>1</sup>, Kobayashi H<sup>2</sup>, Madani M<sup>2</sup>, Rusnak J<sup>1</sup>, Takahashi M<sup>2</sup>, Mikula M<sup>3</sup>, Brunner R<sup>1</sup>

1. Institute of Physics SAS, Dubravská cesta 9, 845 11 Bratislava, Slovak Republic; 2. ISIR, Osaka University, 8-1 Mihogaoka, Ibaraki, Osaka 567-0047, Japan; 3. Faculty of Chemical and Food Technology and Applied Photochemistry, Radlinskeho 9, SUT, 812 39 Bratislava, Slovak Republic

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**摘要** 研究了湿化学法(120 °C硝酸氧化,还有低温湿法氧化过程和高温退火组合)制备的极薄氧化物/6H-SiC结构的电学和光学性质。用深能阶暂态光谱学(电荷版)分析了电界面性质,用傅里叶变换衰减全反射红外光谱考察了极薄氧化物/6H-SiC结构的光学性质。发现界面缺陷结构的强转换依赖于应用的技术条件。

**关键词:** 碳化硅 MOS 硝酸氧化 傅里叶变换红外光谱 深能阶瞬态光谱

**Abstract:** The study deals with electrical and optical properties of very thin oxide/6H-SiC structures prepared by wet chemical manner-nitric acid oxidation at 120 °C and also by combination of low temperature wet oxidation process and higher temperature annealing. For analysis of electrical interface properties, charge version of deep level transient spectroscopy was used. Optical properties of very thin oxide/6H-SiC structures were investigated by fourier transform infrared spectroscopy-attenuated total reflection. Strong transformations of interface defect structure were recognized in dependence on applied technological conditions.

**Keywords:** silicon carbide, MOS, nitric acid oxidation, fourier transform infrared spectroscopy, deep level transient spectroscopy

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## 基金资助:

日本学术振兴会(JSPS)、斯洛伐克基金会: APVV- 项目编号0577/07和 VEGA-项目编号2/0123/09

## 通讯作者 Pincik E

## 引用本文:

.极薄氧化物/6H-SiC结构的电学和光学性质研究[J] 冶金分析, 2011,V31(12): 15-20

.On electrical and optical properties of very thin oxide/6H-SiC structures[J], 2011,V31(12): 15-20

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